

Day : Monday
Date: 3/20/2006

Time: 13:09:38

 PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = NISHIDA

First Name = SHOJI

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>06382708</u>	<u>4456304</u>	150	05/27/1982	SHIELD TUNNELING MACHINE AND EARTH REMOVING APPARATUS THEREFOR	NISHIDA, SHOJI
<u>07354716</u>	<u>5002796</u>	150	05/22/1989	PROCESS FOR FORMING FUNCTIONAL ZINC OXIDE FILMS USING ALKYL ZINC COMPOUND AND OXYGEN- CONTAINING GAS	NISHIDA, SHOJI
<u>07355642</u>	Not Issued	166	05/23/1989	PROCESS FOR THE FORMATION OF A SILICON- CONTAINING SEMICONDUCTOR THIN FILM BY CHEMICALLY REACTING ACTIVE HYDROGEN ATOMS WITH LIQUEFIED FILM- FORMING RAW MATERIAL GAS ON THE SURFACE OF A SUBSTRATE	NISHIDA, SHOJI
<u>07425350</u>	<u>4927786</u>	150	10/20/1989	PROCESS FOR THE FORMATION OF A SILICON- CONTAINING SEMICONDUCTOR THIN FILM BY CHEMICALLY REACTING ACTIVE HYDROGEN ATOMS WITH LIQUEFIED FILM- FORMING RAW MATERIAL GAS ON THE SURFACE OF A SUBSTRATE	NISHIDA, SHOJI
<u>07537818</u>	<u>5098850</u>	150	06/14/1990	PROCESS FOR PRODUCING SUBSTRATE FOR SELECTIVE CRYSTAL GROWTH, SELECTIVE CRYSTAL GROWTH PROCESS AND PROCESS FOR PRODUCING	NISHIDA, SHOJI

				SOLAR BATTERY BY USE OF THEM	
<u>07623526</u>	<u>5103851</u>	150	12/07/1990	SOLAR BATTERY AND METHOD OF MANUFACTURING THE SAME	NISHIDA, SHOJI
<u>07794462</u>	<u>5254481</u>	250	11/19/1991	POLYCRYSTALLINE SOLAR CELL MANUFACTURING METHOD	NISHIDA, SHOJI
<u>07837976</u>	<u>5279686</u>	250	02/20/1992	SOLAR CELL AND METHOD FOR PRODUCING THE SAME	NISHIDA, SHOJI
<u>07887821</u>	<u>5269852</u>	250	05/26/1992	CRYSTALLINE SOLAR CELL AND METHOD FOR PRODUCING THE SAME	NISHIDA, SHOJI
<u>07915693</u>	Not Issued	166	07/27/1992	PROCESS FOR PRODUCING A THIN SILICON SOLAR CELL	NISHIDA, SHOJI
<u>07920497</u>	Not Issued	166	09/28/1992	PROCESS FOR PRODUCING A SOLAR CELL BY MEANS OF EPITAXIAL GROWTH PROCESS	NISHIDA, SHOJI
<u>08010627</u>	Not Issued	166	01/28/1993	A SEMICONDUCTOR DEVICE SUBSTRATE BY BONDING A POROUS LAYER AND AN AMORPHOUS LAYER	NISHIDA, SHOJI
<u>08190584</u>	<u>5403771</u>	150	02/02/1994	PROCESS FOR PRODUCING A SOLAR CELL BY MEANS OF EPITAXIAL GROWTH PROCESS	NISHIDA, SHOJI
<u>08262381</u>	<u>5403751</u>	150	06/20/1994	PROCESS FOR PRODUCING A THIN SILICON SOLAR CELL	NISHIDA, SHOJI
<u>08284265</u>	Not Issued	166	08/02/1994	METHOD FOR PRODUCING SEMICONDUCTOR DEVICE SUBSTRATE BY BONDING A POROUS LAYER AND AN AMORPHOUS LAYER	NISHIDA, SHOJI
<u>08352034</u>	<u>5575862</u>	250	11/30/1994	POLYCRYSTALLINE SILICON PHOTOELECTRIC CONVERSION DEVICE AND PROCESS FOR ITS PRODUCTION	NISHIDA, SHOJI
<u>08369325</u>	<u>5492859</u>	150	01/06/1995	METHOD FOR PRODUCING SEMICONDUCTOR DEVICE SUBSTRATE BY BONDING A POROUS LAYER AND AN AMORPHOUS LAYER	NISHIDA, SHOJI
<u>08406157</u>	<u>5584941</u>	150	03/17/1995	SOLAR CELL AND	NISHIDA, SHOJI

				PRODUCTION PROCESS THEREFOR	
<u>08932708</u>	<u>6387780</u>	150	09/18/1997	FABRICATION PROCESS OF SOLAR CELL	NISHIDA, SHOJI
<u>08993034</u>	<u>6100166</u>	150	12/18/1997	PROCESS FOR PRODUCING SEMICONDUCTOR ARTICLE	NISHIDA, SHOJI
<u>08999132</u>	<u>6190937</u>	150	12/29/1997	METHOD OF PRODUCING SEMICONDUCTOR MEMBER AND METHOD OF PRODUCING SOLAR CELL	NISHIDA, SHOJI
<u>09046600</u>	<u>6258698</u>	150	03/24/1998	PROCESS FOR PRODUCING SEMICONDUCTOR SUBSTRATE	NISHIDA, SHOJI
<u>09047325</u>	<u>6211038</u>	150	03/25/1998	SEMICONDUCTOR DEVICE, AND METHOD FOR MANUFACTURING THE SAME	NISHIDA, SHOJI
<u>09198263</u>	<u>6429035</u>	150	11/24/1998	METHOD OF GROWING SILICON CRYSTAL IN LIQUID PHASE AND METHOD OF PRODUCING SOLAR CELL	NISHIDA, SHOJI
<u>09200867</u>	<u>6231667</u>	150	11/27/1998	LIQUID PHASE GROWTH METHOD AND LIQUID PHASE GROWTH APPARATUS	NISHIDA, SHOJI
<u>09208377</u>	<u>6391108</u>	150	12/10/1998	LIQUID PHASE GROWTH METHOD OF SILICON CRYSTAL, METHOD OF PRODUCING SOLAR CELL, AND LIQUID PHASE GROWTH APPARATUS	NISHIDA, SHOJI
<u>09310953</u>	<u>6248948</u>	150	05/13/1999	SOLAR CELL MODULE AND METHOD OF PRODUCING THE SAME	NISHIDA, SHOJI
<u>09310954</u>	<u>6331208</u>	150	05/13/1999	PROCESS FOR PRODUCING SOLAR CELL, PROCESS FOR PRODUCING THIN-FILM SEMICONDUCTOR, PROCESS FOR SEPARATING THIN-FILM SEMICONDUCTOR, AND PROCESS FOR FORMING SEMICONDUCTOR	NISHIDA, SHOJI
<u>09346678</u>	Not Issued	161	07/02/1999	CRYSTAL GROWTH PROCESS, SEMICONDUCTOR DEVICE, AND ITS PRODUCTION PROCESS	NISHIDA, SHOJI
<u>09401775</u>	<u>6391743</u>	150	09/22/1999	METHOD AND APPARATUS	NISHIDA, SHOJI

				FOR PRODUCING PHOTOELECTRIC CONVERSION DEVICE	
<u>09572940</u>	<u>6534336</u>	150	05/18/2000	PRODUCTION METHOD OF PHOTOELECTRIC CONVERSION DEVICE, AND PHOTOELECTRIC CONVERSION DEVICE PRODUCED BY THE METHOD	NISHIDA, SHOJI
<u>09586887</u>	<u>6664169</u>	150	06/05/2000	PROCESS FOR PRODUCING SEMICONDUCTOR MEMBER, PROCESS FOR PRODUCING SOLAR CELL, AND ANODIZING APPARATUS	NISHIDA, SHOJI
<u>09592559</u>	<u>6448155</u>	150	06/12/2000	PRODUCTION METHOD OF SEMICONDUCTOR BASE MATERIAL AND PRODUCTION METHOD OF SOLAR CELL	NISHIDA, SHOJI
<u>09634542</u>	<u>6534382</u>	150	08/08/2000	PROCESS FOR PRODUCING SEMICONDUCTOR ARTICLE	NISHIDA, SHOJI
<u>09638398</u>	<u>6756289</u>	150	08/15/2000	METHOD OF PRODUCING SEMICONDUCTOR MEMBER AND METHOD OF PRODUCING SOLAR CELL	NISHIDA, SHOJI
<u>09656014</u>	<u>6682990</u>	150	09/07/2000	SEPARATION METHOD OF SEMICONDUCTOR LAYER AND PRODUCTION METHOD OF SOLAR CELL	NISHIDA, SHOJI
<u>09662604</u>	<u>6500731</u>	150	09/14/2000	PROCESS FOR PRODUCING SEMICONDUCTOR DEVICE MODULE	NISHIDA, SHOJI
<u>09664340</u>	<u>6566277</u>	150	09/18/2000	LIQUID-PHASE GROWTH METHOD, LIQUID-PHASE GROWTH APPARATUS, AND SOLAR CELL	NISHIDA, SHOJI
<u>09764400</u>	Not Issued	161	01/19/2001	Semiconductor device, and method for manufacturing the same	NISHIDA, SHOJI
<u>09769329</u>	<u>6602767</u>	150	01/26/2001	METHOD FOR TRANSFERRING POROUS LAYER, METHOD FOR MAKING SEMICONDUCTOR DEVICES, AND METHOD FOR MAKING SOLAR BATTERY	NISHIDA, SHOJI
<u>09790589</u>	<u>6384313</u>	150	02/23/2001	Solar cell module and method of	NISHIDA, SHOJI

				producing the same	
<u>09819680</u>	<u>6566235</u>	150	03/29/2001	PROCESS FOR PRODUCING SEMICONDUCTOR MEMBER, AND PROCESS FOR PRODUCING SOLAR CELL	NISHIDA, SHOJI
<u>09927406</u>	Not Issued	161	08/13/2001	Fabrication process of solar cell	NISHIDA, SHOJI
<u>09964332</u>	<u>6551908</u>	150	09/28/2001	METHOD FOR PRODUCING SEMICONDUCTOR THIN FILMS ON MOVING SUBSTRATES	NISHIDA, SHOJI
<u>09978633</u>	<u>6953506</u>	150	10/18/2001	WAFER CASSETTE, AND LIQUID-PHASE GROWTH SYSTEM AND LIQUID-PHASE GROWTH PROCESS WHICH MAKE USE OF THE SAME	NISHIDA, SHOJI
<u>10014418</u>	<u>7022181</u>	150	12/14/2001	LIQUID PHASE GROWTH PROCESS, LIQUID PHASE GROWTH SYSTEM AND SUBSTRATE MEMBER PRODUCTION METHOD	NISHIDA, SHOJI
<u>10022545</u>	<u>6802900</u>	150	12/20/2001	LIQUID PHASE GROWTH METHODS AND LIQUID PHASE GROWTH APPARATUS	NISHIDA, SHOJI
<u>10083585</u>	<u>6720237</u>	150	02/27/2002	METHOD FOR MANUFACTURING A SEMICONDUCTOR FILM	NISHIDA, SHOJI
<u>10120357</u>	Not Issued	161	04/12/2002	Liquid phase growth method of silicon crystal, method of producing solar, cell, and liquid phase growth apparatus	NISHIDA, SHOJI
<u>10229123</u>	<u>6824609</u>	150	08/28/2002	LIQUID PHASE GROWTH METHOD AND LIQUID PHASE GROWTH APPARATUS	NISHIDA, SHOJI

[Search and Display More Records.](#)

Search Another: Inventor	Last Name	First Name	
	<input type="text" value="Nishida"/>	<input type="text" value="Shoji"/>	<input type="button" value="Search"/>

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | [Home page](#)

Day : Monday
Date: 3/20/2006

Time: 13:09:53



PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = YOSHINO

First Name = TAKEHITO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>07111768</u>	Not Issued	166	10/23/1987	LIGHT RECEIVING MEMBER HAVING A DIVIDED-FUNCTIONALLY STRUCTURED LIGHT RECEIVING LAYER HAVING CGL AND CTL FOR USE IN ELECTROPPHOTOGRAPHY	YOSHINO, TAKEHITO
<u>07182156</u>	4886723	150	04/15/1988	LIGHT RECEIVING MEMBER HAVING A MULTILAYERED LIGHT RECEIVING LAYER COMPOSED OF A LOWER LAYER MADE OF ALUMINUM-CONTAINING INORGANIC MATERIAL AND AN UPPER LAYER MADE OF NON-SINGLE-CRYSTAL SILICON MATERIAL	YOSHINO, TAKEHITO
<u>07183701</u>	4882251	150	04/19/1988	LIGHT RECEIVING MEMBER HAVING A MULTILAYERED LIGHT RECEIVING LAYER COMPOSED OF A LOWER LAYER MADE OF ALUMINUM-CONTAINING INORGANIC MATERIAL AND AN UPPER LAYER MADE OF NON-SINGLE-CRYSTAL SILICON MATERIAL	YOSHINO, TAKEHITO
<u>07183998</u>	4906542	150	04/20/1988	LIGHT RECEIVING MEMBER HAVING A MULTILAYERED LIGHT RECEIVING LAYER COMPOSED OF A LOWER LAYER MADE OF ALUMINUM-CONTAINING INORGANIC MATERIAL AND AN UPPER LAYER MADE OF NON-SINGLE-CRYSTAL SILICON MATERIAL	YOSHINO, TAKEHITO
<u>07184872</u>	4906543	150	04/21/1988	LIGHT RECEIVING MEMBER	YOSHINO,

				HAVING A MULTILAYERED LIGHT RECEIVING LAYER COMPOSED OF A LOWER LAYER MADE OF ALUMINUM-CONTAINING INORGANIC MATERIAL AND AN UPPER LAYER MADE OF NON-SINGLE-CRYSTAL SILICON MATERIAL	TAKEHITO
<u>07403396</u>	<u>4981766</u>	150	09/06/1989	LIGHT RECEIVING MEMBER HAVING A MULTILAYERED LIGHT RECEIVING LAYER COMPOSED OF A LOWER LAYER MADE OF ALUMINUM-CONTAINING INORGANIC MATERIAL AND AN UPPER LAYER MADE OF NON-SINGLE-CRYSTAL SILICON MATERIAL	YOSHINO, TAKEHITO
<u>07423680</u>	<u>4954397</u>	150	10/18/1989	LIGHT RECEIVING MEMBER HAVING A DIVIDED-FUNCTIONALLY STRUCTURED LIGHT RECEIVING LAYER HAVING CGL AND CTL FOR USE IN ELECTROPHOTOGRAPHY	YOSHINO, TAKEHITO
<u>07455227</u>	<u>5087542</u>	150	12/21/1989	ELECTROPHOTOGRAPHIC IMAGE-FORMING METHOD WHEREIN AN AMORPHOUS SILICON LIGHT RECEIVING MEMBER WITH A LATENT IMAGE SUPPORT LAYER AND A DEVELOPED IMAGE SUPPORT LAYER AND FINE PARTICLE INSULATING TONER ARE USED	YOSHINO, TAKEHITO
<u>07456741</u>	Not Issued	161	12/26/1989	ELECTROPHOTOGRAPHIC IMAGE-FORMING METHOD WHEREIN AN AMORPHOUS SILICON LIGHT RECEIVING MEMBER WITH A LATENT IMAGE SUPPORT LAYER AND A DEVELOPED IMAGE SUPPORT LAYER AND FINE PARTICLE INSULATING TONER HAVING A VOLUME AVERAGE PARTICLE SIZE OF 4.5 TO 9.0 MICRON AND AN	YOSHINO, TAKEHITO
<u>07811925</u>	Not Issued	166	12/23/1991	ELECTROPHOTOGRAPHIC IMAGE-FORMING METHOD	YOSHINO, TAKEHITO

				WHEREIN AN AMORPHOUS SILICON LIGHT RECEIVING MEMBER WITH A LATENT IMAGE SUPPORT LAYER AND A DEVELOPED IMAGE SUPPORT LAYER AND FINE PARTICLE INSULATING TONER HAVING A VOLUME AVERAGE PARTICLE SIZE OF 4.5 TO 9.0 MICRON AND AN	
<u>07858410</u>	<u>5266116</u>	250	03/27/1992	GLOW DISCHARGE APPARATUS FOR CONTINUOUSLY MANUFACTURING SEMICONDUCTOR DEVICE COMPRISING GAS GATES WITH SLOTTED ROLLERS	YOSHINO, TAKEHITO
<u>07935356</u>	Not Issued	166	08/28/1992	ELECTROPHOTOGRAPHIC IMAGE-FORMING METHOD WHEREIN AN AMORPHOUS SILICON LIGHT RECEIVING MEMBER WITH A LATENT IMAGE SUPPORT LAYER AND A DEVELOPED IMAGE SUPPORT LAYER AND FINE PARTICLE INSULATING TONER HAVING A VOLUME AVERAGE PARTICLE SIZE OF 4.5 TO 9.0 MICRON AND AN APPA	YOSHINO, TAKEHITO
<u>07967238</u>	Not Issued	166	10/27/1992	DEPOSITED FILM FORMING METHOD AND DEPOSITED FILM FORMING APPARATUS	YOSHINO, TAKEHITO
<u>08053822</u>	<u>5358811</u>	150	04/29/1993	ELECTROPHOTOGRAPHIC METHOD USING AN AMORPHOUS SILICON LIGHT RECEIVING MEMBER WITH A LATENT IMAGE SUPPORT LAYER AND A DEVELOPED IMAGE SUPPORT LAYER AND INSULATING TONER HAVING A VOLUME AVERAGE PARTICLE SIZE OF 4.5 TO 9.0 MICRONS	YOSHINO, TAKEHITO
<u>08070476</u>	Not Issued	161	10/14/1993	CONTINUOUSLY FILM-FORMING APPARATUS PROVIDED WITH IMPROVED GAS GATE MEANS	YOSHINO, TAKEHITO
<u>08097046</u>	<u>5382531</u>	150	07/27/1993	METHOD FOR CONTINUOUSLY MANUFACTURING A	YOSHINO, TAKEHITO

				SEMICONDUCTOR DEVICE	
<u>08101018</u>	Not Issued	166	08/03/1993	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION APPARATUS	YOSHINO, TAKEHITO
<u>08196111</u>	<u>5624776</u>	250	02/18/1994	ELECTROPHOTOGRAPHIC PHOTOSENSITIVE MEMBER PROVIDED WITH A LIGHT RECEIVING LAYER COMPOSED OF A NON-SINGLE CRYSTAL SILICON MATERIAL CONTAINING COLUMNAR STRUCTURE REGIONS AND PROCESS FOR THE PRODUCTION THEREOF	YOSHINO, TAKEHITO
<u>08334032</u>	<u>5468521</u>	150	11/02/1994	METHOD FOR FORMING A PHOTOELECTRIC DEPOSITED FILM	YOSHINO, TAKEHITO
<u>08404616</u>	Not Issued	166	03/15/1995	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION APPARATUS	YOSHINO, TAKEHITO
<u>08416468</u>	Not Issued	166	04/04/1995	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION THEREOF	YOSHINO, TAKEHITO
<u>08433052</u>	<u>5575855</u>	250	05/03/1995	APPARATUS FOR FORMING A DEPOSITED FILM	YOSHINO, TAKEHITO
<u>08610076</u>	<u>5919310</u>	150	02/29/1996	CONTINUOUSLY FILM- FORMING APPARATUS PROVIDED WITH IMPROVED GAS GATE MEANS	YOSHINO, TAKEHITO
<u>08704138</u>	<u>6273955</u>	150	08/28/1996	FILM FORMING APPARATUS AND METHOD	YOSHINO, TAKEHITO
<u>08741352</u>	<u>5946587</u>	150	10/29/1996	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS	YOSHINO, TAKEHITO
<u>08754066</u>	<u>5968274</u>	150	11/20/1996	CONTINUOUS FORMING METHOD FOR FUNCTIONAL DEPOSITED FILMS AND DEPOSITION APPARATUS	YOSHINO, TAKEHITO
<u>08768609</u>	<u>6350489</u>	150	12/18/1996	DEPOSITED-FILM FORMING PROCESS AND DEPOSITED- FILM FORMING APPARATUS	YOSHINO, TAKEHITO
<u>08814081</u>	<u>6113732</u>	150	03/10/1997	DEPOSIT FILM FORMING APPARATUS	YOSHINO, TAKEHITO

<u>08907613</u>	<u>5993582</u>	150	08/08/1997	CONTINUOUS VACUUM LAMINATION TREATMENT SYSTEM AND VACUUM LAMINATION APPARATUS	YOSHINO, TAKEHITO
<u>09106469</u>	<u>6169414</u>	150	06/30/1998	MEASURING APPARATUS AND METHOD FOR MEASURING CHARACTERISTIC OF SOLAR CELL	YOSHINO, TAKEHITO
<u>09245310</u>	<u>6241839</u>	150	02/05/1999	CONTINUOUS VACUUM LAMINATION TREATMENT SYSTEM AND VACUUM LAMINATION APPARATUS	YOSHINO, TAKEHITO
<u>09255842</u>	<u>6265242</u>	150	02/23/1999	SOLAR CELL MODULE AND A PROCESS FOR PRODUCING SAID SOLAR CELL MODULE	YOSHINO, TAKEHITO
<u>09327569</u>	<u>6184458</u>	150	06/08/1999	PHOTOVOLTAIC ELEMENT AND PRODUCTION METHOD THEREFOR	YOSHINO, TAKEHITO
<u>09330601</u>	<u>6162986</u>	150	06/11/1999	SOLAR CELL MODULE AND METHOD OF MANUFACTURING THE SAME	YOSHINO, TAKEHITO
<u>09332104</u>	<u>6180868</u>	150	06/14/1999	SOLAR CELL MODULE, SOLAR CELL MODULE STRING, SOLAR CELL SYSTEM, AND METHOD FOR SUPERVISING SAID SOLAR CELL MODULE OR SOLAR CELL MODULE STRING	YOSHINO, TAKEHITO
<u>09337557</u>	<u>6338872</u>	150	06/22/1999	FILM FORMING METHOD	YOSHINO, TAKEHITO
<u>09470211</u>	<u>6271462</u>	150	12/22/1999	INSPECTION METHOD AND PRODUCTION METHOD OF SOLAR CELL MODULE	YOSHINO, TAKEHITO
<u>09691130</u>	<u>6639421</u>	150	10/19/2000	MEASURING APPARATUS AND METHOD FOR MEASURING CHARACTERISTIC OF SOLAR CELL	YOSHINO, TAKEHITO
<u>09717238</u>	<u>6515218</u>	150	11/22/2000	PHOTOVOLTAIC ELEMENT, PROCESS FOR THE PRODUCTION THEREOF, METHOD FOR REMOVING A COVER PORTION OF A COVERED WIRE, AND METHOD FOR JOINING A COVERED WIRE AND A CONDUCTOR	YOSHINO, TAKEHITO
<u>09964332</u>	<u>6551908</u>	150	09/28/2001	METHOD FOR PRODUCING SEMICONDUCTOR THIN FILMS	YOSHINO, TAKEHITO

				ON MOVING SUBSTRATES	
09978633	6953506	150	10/18/2001	WAFER CASSETTE, AND LIQUID-PHASE GROWTH SYSTEM AND LIQUID-PHASE GROWTH PROCESS WHICH MAKE USE OF THE SAME	YOSHINO, TAKEHITO
10014418	7022181	150	12/14/2001	LIQUID PHASE GROWTH PROCESS, LIQUID PHASE GROWTH SYSTEM AND SUBSTRATE MEMBER PRODUCTION METHOD	YOSHINO, TAKEHITO
10022545	6802900	150	12/20/2001	LIQUID PHASE GROWTH METHODS AND LIQUID PHASE GROWTH APPARATUS	YOSHINO, TAKEHITO
10229123	6824609	150	08/28/2002	LIQUID PHASE GROWTH METHOD AND LIQUID PHASE GROWTH APPARATUS	YOSHINO, TAKEHITO
10364517	6951584	150	02/12/2003	APPARATUS FOR PRODUCING SEMICONDUCTOR THIN FILMS ON MOVING SUBSTRATES	YOSHINO, TAKEHITO
10385457	7014711	150	03/12/2003	LIQUID-PHASE GROWTH APPARATUS AND METHOD	YOSHINO, TAKEHITO
10400636	6872248	150	03/28/2003	LIQUID-PHASE GROWTH PROCESS AND LIQUID-PHASE GROWTH APPARATUS	YOSHINO, TAKEHITO
10505979	Not Issued	41	08/27/2004	Process of producing multicrystalline silicon substrate and solar cell	YOSHINO, TAKEHITO
10670301	Not Issued	41	09/26/2003	Method for growing silicon film, method for manufacturing solar cell, semiconductor substrate, and solar cell	YOSHINO, TAKEHITO
10676094	Not Issued	71	10/02/2003	Liquid phase growth method for silicon crystal, manufacturing method for solar cell and liquid phase growth apparatus for silicon crystal	YOSHINO, TAKEHITO

[Search and Display More Records.](#)

Search Another: Inventor

Last Name

First Name

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | [Home page](#)

Day : Monday
Date: 3/20/2006

Time: 13:10:13


PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = IWANE

First Name = MASA AKI

Application#	Patent#	Status	Date Filed	Title	Inventor Name
08658080	6140985	150	06/04/1996	IMAGE DISPLAY APPARATUS	IWANE, MASA AKI
09045955	6140209	150	03/23/1998	PROCESS FOR FORMING AN SOI SUBSTRATE	IWANE, MASA AKI
09047336	6133112	150	03/25/1998	THIN FILM FORMATION PROCESS	IWANE, MASA AKI
09198263	6429035	150	11/24/1998	METHOD OF GROWING SILICON CRYSTAL IN LIQUID PHASE AND METHOD OF PRODUCING SOLAR CELL	IWANE, MASA AKI
09200867	6231667	150	11/27/1998	LIQUID PHASE GROWTH METHOD AND LIQUID PHASE GROWTH APPARATUS	IWANE, MASA AKI
09208377	6391108	150	12/10/1998	LIQUID PHASE GROWTH METHOD OF SILICON CRYSTAL, METHOD OF PRODUCING SOLAR CELL, AND LIQUID PHASE GROWTH APPARATUS	IWANE, MASA AKI
09310954	6331208	150	05/13/1999	PROCESS FOR PRODUCING SOLAR CELL, PROCESS FOR PRODUCING THIN-FILM SEMICONDUCTOR, PROCESS FOR SEPARATING THIN-FILM SEMICONDUCTOR, AND PROCESS FOR FORMING SEMICONDUCTOR	IWANE, MASA AKI
09346678	Not Issued	161	07/02/1999	CRYSTAL GROWTH PROCESS, SEMICONDUCTOR DEVICE, AND ITS PRODUCTION PROCESS	IWANE, MASA AKI
09401775	6391743	150	09/22/1999	METHOD AND APPARATUS FOR PRODUCING PHOTOELECTRIC	IWANE, MASA AKI

				CONVERSION DEVICE	
<u>09572940</u>	<u>6534336</u>	150	05/18/2000	PRODUCTION METHOD OF PHOTOELECTRIC CONVERSION DEVICE, AND PHOTOELECTRIC CONVERSION DEVICE PRODUCED BY THE METHOD	IWANE, MASA AKI
<u>09614548</u>	<u>6452091</u>	150	07/12/2000	METHOD OF PRODUCING THIN-FILM SINGLE-CRYSTAL DEVICE, SOLAR CELL MODULE AND METHOD OF PRODUCING THE SAME	IWANE, MASA AKI
<u>09635246</u>	<u>6534383</u>	150	08/09/2000	THIN FILM FORMATION PROCESS BY CLEARING THE IMPLANTED LAYER WITH LASER RADIATION	IWANE, MASA AKI
<u>09656014</u>	<u>6682990</u>	150	09/07/2000	SEPARATION METHOD OF SEMICONDUCTOR LAYER AND PRODUCTION METHOD OF SOLAR CELL	IWANE, MASA AKI
<u>09964332</u>	<u>6551908</u>	150	09/28/2001	METHOD FOR PRODUCING SEMICONDUCTOR THIN FILMS ON MOVING SUBSTRATES	IWANE, MASA AKI
<u>09978633</u>	<u>6953506</u>	150	10/18/2001	WAFER CASSETTE, AND LIQUID-PHASE GROWTH SYSTEM AND LIQUID-PHASE GROWTH PROCESS WHICH MAKE USE OF THE SAME	IWANE, MASA AKI
<u>10014418</u>	<u>7022181</u>	150	12/14/2001	LIQUID PHASE GROWTH PROCESS, LIQUID PHASE GROWTH SYSTEM AND SUBSTRATE MEMBER PRODUCTION METHOD	IWANE, MASA AKI
<u>10022545</u>	<u>6802900</u>	150	12/20/2001	LIQUID PHASE GROWTH METHODS AND LIQUID PHASE GROWTH APPARATUS	IWANE, MASA AKI
<u>10120357</u>	Not Issued	161	04/12/2002	Liquid phase growth method of silicon crystal, method of producing solar, cell, and liquid phase growth apparatus	IWANE, MASA AKI
<u>10259285</u>	Not Issued	161	09/30/2002	Crystal growth process, semiconductor device, and its production process	IWANE, MASA AKI

<u>10364517</u>	<u>6951584</u>	150	02/12/2003	APPARATUS FOR PRODUCING SEMICONDUCTOR THIN FILMS ON MOVING SUBSTRATES	IWANE, MASA AKI
<u>10505979</u>	Not Issued	41	08/27/2004	Process of producing multicrystalline silicon substrate and solar cell	IWANE, MASA AKI
<u>10676094</u>	Not Issued	71	10/02/2003	Liquid phase growth method for silicon crystal, manufacturing method for solar cell and liquid phase growth apparatus for silicon crystal	IWANE, MASA AKI
<u>10957577</u>	Not Issued	30	10/05/2004	Electrode arranging method	IWANE, MASA AKI

Inventor Search Completed: No Records to Display.

Search Another: Inventor	Last Name	First Name	<input type="button" value="Search"/>
	<input type="text" value="Iwane"/>	<input type="text" value="Masaaki"/>	

To go back use Back button on your browser toolbar.

Back to [PALM](#) | [ASSIGNMENT](#) | [OASIS](#) | [Home page](#)